1 General Information

Equipment Code:	ENDURA PVD
Model Number:	5500
Software Version:	B8.91
Vintage:	2000

Wafer Specification

2

Wafer Size:	☐ 150mm	☑ 200mm
Wafer Shape:	☑ Notch	
SMIF Interface:	☑ YES	☐ NO

3 SYSTEM INFORMATION

- ☐ CHAMBER A (PRE-CLEAN CHAMBER)
- ☐ CHAMBER B (COOLDOWN CHAMBER)
- ☐ CHAMBER C
- ☐ CHAMBER D
- ☑ CHAMBER E (DEGAS/ORIENTAL CHAMBER)
- ☐ CHAMBER F (COOLDOWN CHAMBER)
- ☐ CHAMBER 1
- ☐ CHAMBER 2
- ☐ CHAMBER 3
- ☐ CHAMBER 4
- ☑ BUFFER CHAMBER
- ☑ TRANSFER CHAMBER

Loadlock Type: ☑ NARROW BODY ☐ WIDE BODY

4 CHAMBER TYPE

4.1 Chamber A Information

4.2 Chamber B Information

Chanber Type:	Cooldown Chamber
Pump:	CTI-Cryogenic On Board
Rough Pump:	Trivac Leybold
Valve Type:	VAT
Convectron:	Granville Phillips

4.3 Chamber C Information

Chamber Process: _____
Convectron Gauge: _____
Rough Pump: _____
HVAC Pump: _____
Cryo Compressor: _____
Pressure Transducer: _____
RF Gen 1: _____
RF Gen 2: _____
WTM/ESC: _____

4.4 Chamber D Information

Chamber Process: _____
Convectron Gauge: _____
Rough Pump: _____
HVAC Pump: _____
Cryo Compressor: _____
Pressure Transducer: _____
RF Gen 1: _____
RF Gen 2: _____
WTM/ESC: _____

4.5 Chamber E Information

4.6 Chamber F Information

4.7 Chamber 1 Information

Chamber Process: _____
Convectron Gauge: _____
Rough Pump: _____
HVAC Pump: _____
Cryo Compressor: _____
Pressure Transducer: _____
ION Guage: _____
RF Gen 1: _____
RF Gen 2: _____
RF Gen 3: _____
WTM/ESC: _____

4.8 Chamber 2 Information

Chamber Process: _____
Convectron Gauge: _____
Rough Pump: _____

HVAC Pump: _____
Cryo Compressor: _____
Pressure Transducer: _____
ION Guage: _____
RF Gen 1: _____
RF Gen 2: _____
RF Gen 3: _____
WTM/ESC: _____

4.9 Chamber 3 Information
Chamber Process: _____
Convectron Gauge: _____
Rough Pump: _____
HVAC Pump: _____
Cryo Compressor: _____
Pressure Transducer: _____
ION Guage: _____
RF Gen 1: _____
RF Gen 2: _____
RF Gen 3: _____
WTM/ESC: _____

4.10 Chamber 4 Information
Chamber Process: _____
Convectron Gauge: _____
Rough Pump: _____
HVAC Pump: _____
Cryo Compressor: _____
Pressure Transducer: _____
ION Guage: _____
RF Gen 1: _____
RF Gen 2: _____
RF Gen 3: _____
WTM/ESC: _____

4.11 Buffer Chamber Information
Rough Pump: _____
Valve Type: _____
Convectron: _____
Robot: _____

4.12 Transfer Chamber Information
Rough Pump: _____

Valve Type:
Convectron:
Robot:

5 Electrical

Line Frequency:	☑ 50Hz	☐ 60Hz
Line Voltage:	☑ 200/208V	☐ 480 V
Line Amperage:	☑ 320A	☐ 69.5A

6 Mainframe Information

Syetem Placement:
Robot Type Buffer:
Robot Type Transfer:
Robot Blade:
Wafer Transfer Loadlock:
Wafer Mapping:

7 Generator Rack

Rack #1

Item	Present?
Remote +- 15V Power Supply	
AE MDX-L 12M-650	

Rack #2

Item	Present?

8 E-Chuck Information

CH 2&3 AC ON BOARD
CH 2 1.5KV DC BUS CARD
CH 3 1.5KV DC BUS CARD

9 CHILLER SYSTEM

Chiller Type: Neslab

10 MFC

CHM C, CHM 1 & CHM 2

MFC 1 _____
MFC 2 _____
MFC 3 _____
MFC 4 _____
MFC 5 _____
MFC 6 _____
MFC 7 _____
MFC 8 _____
MFC 9 _____

CHM D. CHM 3 & CHM 4

MFC 1 _____
MFC 2 _____
MFC 3 _____
MFC 4 _____
MFC 5 _____
MFC 6 _____
MFC 7 _____
MFC 8 _____
MFC 9 _____

11 System Controller

Slot #	Top Rack BD	Present
1	System Reset	
2	Serial Isolater	
3	VGA VIDEO	
4	OMS	
5	DI/O	
6	DI/O	
7	DI/0	
8	DI/O	
9	DI/O	
10	DI/O	
11	SEI BOARD	
12	BLANK	
13	BLANK	
14	BLANK	
15	STEP CONT	
16	STEP CONT	
17	STEP CONT	
18	STEP CONT	
19	AI	
20	AO	
21	AO	
22		
23		
24		
25		

Slot #	Bottom Rack BD
22	Hard Disk Drive
23	BLANK
24	BLANK
25	332103 VGC
26	332103 VGC
27	332103 VGC
28	332103 VGC
29	5CH TC GAUGE
30	5CH TC GAUGE
31	332103 IGC
32	332134 IGC
33	DIO EXPENSION
34	Chamber 1 DI/O
35	Chamber 2 DI/O
36	Chamber 3 DI/O
37	Chamber 4 DI/O
38	Chamber 5 DI/O
39	Chamber C DI/O
40	Chamber D DI/O
41	FLOPPY DRIVE
24	Mainframe DI/O 6
47	BLANK
48	VGC CRYO TEMP
49	VGC AI MUX
50	VGC AI MUX
51	BLANK
52	BLANK
53	TC GAUGE OPTO

54	IGC OPTO
55	IGC OPTO
56	